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**RESPONSE UNDER 37 C.F.R. § 1.116  
EXPEDITED PROCEDURE REQUESTED  
EXAMINING GROUP 2825**

**PATENT**

Attorney Docket No. 03180.0360

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of:	)	
Satoshi Tanaka et al.	)	Group Art Unit: 2825
Application No.: 10/808,299	)	Examiner: MEMULA, Suresh
Filed: March 25, 2004	)	Confirmation No.: 7279
For: SET OF MASKS, METHOD OF GENERATING MASK DATA AND METHOD FOR FORMING A PATTERN	)	Mail Stop AF

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:



**REQUEST FOR RECONSIDERATION**

In reply to the Final Office Action mailed May 18, 2007, the period for response to which extends through August 20, 2007 (August 18th being a Saturday), Applicants request the Examiner's reconsideration in view of the remarks that follow:

**Remarks** begin at page 2 of this paper.